



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/905,320
Filing Date July 13, 2001
Inventor Cem Basceri et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner Eric B. Fuller
Attorney's Docket No. MI22-1657
Customer No. 021567
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium
Titanate Comprising Dielectric Layers, Including Such Layers Having a
Varied Concentration of Barium and Strontium Within the Layer.

PETITION FOR WITHDRAWAL FROM ISSUE FOR ABANDONMENT
TO PERMIT CONSIDERATION OF AN INFORMATION
DISCLOSURE STATEMENT UNDER § 1.97
IN A CONTINUING APPLICATION
(37 C.F.R. § 1.313(5))

To: Office of Petitions
U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

VIA HAND-DELIVERY

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
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130.00 OP

PETITION

Applicant hereby petitions for the withdrawal of this application from
issue.

PATENT ISSUE FEE

The issue fee for this case was paid on May 19, 2004.

The patent issue date is not yet known.

REASON FOR WITHDRAWAL REQUEST

In an abundance of caution, the reason for withdrawal from issue and abandonment of this application is for consideration of information in a continuation application.

EXPRESS ABANDONMENT

Accompanying this Petition is an express abandonment of this application to be effective on the grant of this Petition and when the continuing application is granted a filing date so as to make this application co-pending with the continuing application.


The continuing application claiming priority under 35 U.S.C. § 120 from this application was filed concurrently with this Petition.

PETITION FEES

The Petition fee is paid with the enclosed check in the sum of \$130.00.

Respectfully submitted,

Dated: 6-25-04

By: 
Mark S. Matkin
Reg. No. 32,268



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**EXPRESS ABANDONMENT TO PERMIT CONSIDERATION OF
INFORMATION DISCLOSURE STATEMENT
IN CONTINUING APPLICATION**
(37 C.F.R. § 1.313)

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Applicant has separately filed a Petition For Withdrawal From Issue of this application to permit consideration of an Information Disclosure Statement under 37 C.F.R. § 1.97 in a continuing application. The continuation application is being filed concurrently with this Petition.

Applicant hereby abandons this application as of the time the Petition To Withdraw From Issue in this application is granted and when the continuing application is granted a filing date so as to make this application co-pending with said continuing application.

Respectfully submitted,

Dated: 6-25-04

By: 

Mark S. Matkin
Reg. No. 32,268